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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

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Art Unit: 1725

Kenji KASAHARA et al.

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Examiner: G. Evans

Serial No. 09/640,521

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Filed: August 17, 2000

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For: LASER APPARATUS AND

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LASER ANNEALING METHOD

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with The United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on January 17, 2003.

Adele M. Stamper
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SUPPLEMENTAL AMENDMENT

Honorable Commissioner of Patents

Washington, D.C. 20231

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Technology Center 2800

Sir:

Further to the Amendment filed on December 2, 2002, please further amend the above-identified application as follows:

IN THE CLAIMS:

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TC 1700

Please amend claim 30 as follows:

30. (Twice Amended) A laser apparatus, comprising:

a laser source for emitting a laser light;

a half mirror for dividing the laser light into a first laser light and a second laser

light;

an optical system for guiding the first laser light and the second laser light onto

a top surface and a back surface of an object to be treated, respectively,

wherein the optical system includes a filter for attenuating the second laser

light;

a substrate holder for holding a substrate,

wherein a semiconductor film is formed over the substrate.